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Pd-C film for sensor applications					
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ABSTRACT

Characterisation of C-Pd films composed of carbon and palladium nanograins and obtained in two-steps method is presented. Film obtained in first step exhibits multiphase structure composed of nanograins of fullerenes, amorphous carbon and palladium nanocrystals. This film is modified in CVD process. Final films has porous carbonaceous form. All films were studied by scanning electron microscopy (SEM), atomic force microscopy (AFM) and Raman spectroscopy. Structure, molecular structure and topography of obtained films is studied with these methods.

INDEX TERMS

• IEEE Terms

Amorphous materials , Atomic force microscopy , Nanocrystals , Nanostructures , Palladium , Raman scattering , Scanning electron microscopy , Sensor phenomena and characterization , Spectroscopy , Surfaces

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• Controlled Indexing

Raman spectra , atomic force microscopy , chemical vapour deposition , fullerenes , grain size , molecular configurations , nanofabrication , nanoporous materials , palladium , porosity , scanning electron microscopy , surface topography , thin films

• Non Controlled Indexing

AFM , C-Pd , CVD , PVD , Raman spectroscopy , SEM , amorphous carbon , atomic force microscopy , fullerenes , grain size , graphitisation , molecular structure , multiphase structure , nanograins , physical vapor deposition , porosity , scanning electron microscopy , sensor applications , thin films , topography , two-steps method

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